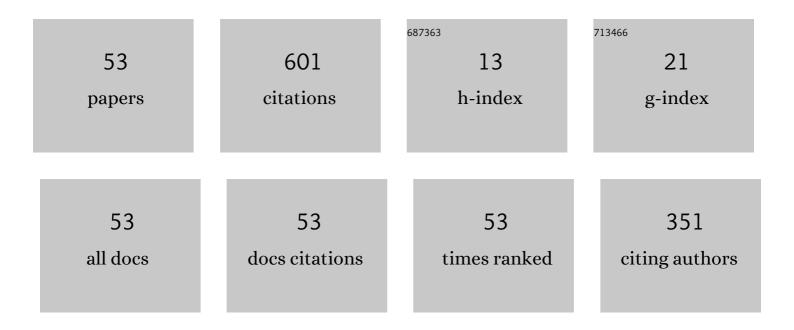
Yingtao Ding

List of Publications by Year in descending order

Source: https://exaly.com/author-pdf/451839/publications.pdf Version: 2024-02-01



| # | Article | IF | CITATIONS |
|----|---|------|-----------|
| 1 | Programmable <scp>vanâ€derâ€Waals</scp> heterostructureâ€enabled optoelectronic synaptic floatingâ€gate transistors with ultraâ€low energy consumption. InformaÄnÃ-Materiály, 2022, 4, . | 17.3 | 58 |
| 2 | Mixedâ€Dimensional Van der Waals Heterostructures Enabled Optoelectronic Synaptic Devices for Neuromorphic Applications. Advanced Functional Materials, 2021, 31, 2105625. | 14.9 | 39 |
| 3 | Recent progress in metasurface-enabled optical waveplates. Nanophotonics, 2022, 11, 2219-2244. | 6.0 | 39 |
| 4 | A Novel Noncircular MUSIC Algorithm Based on the Concept of the Difference and Sum Coarray. Sensors, 2018, 18, 344. | 3.8 | 35 |
| 5 | MEMS Ultrasound Transducers for Endoscopic Photoacoustic Imaging Applications. Micromachines, 2020, 11, 928. | 2.9 | 30 |
| 6 | Optogeneticsâ€Inspired Neuromorphic Optoelectronic Synaptic Transistors with Optically Modulated Plasticity. Advanced Optical Materials, 2021, 9, 2002232. | 7.3 | 28 |
| 7 | A Novel Nested Configuration Based on the Difference and Sum Co-Array Concept. Sensors, 2018, 18, 2988. | 3.8 | 25 |
| 8 | Dualâ€Functional Optical Waveplates Based on Gapâ€&urface Plasmon Metasurfaces. Advanced Optical Materials, 2021, 9, 2002253. | 7.3 | 21 |
| 9 | Electrical Characterization of Coaxial Silicon–Insulator–Silicon Through-Silicon Vias: Theoretical Analysis and Experiments. IEEE Transactions on Electron Devices, 2016, 63, 4880-4887. | 3.0 | 19 |
| 10 | Coprime Nested Arrays for DOA Estimation: Exploiting the Nesting Property of Coprime Array. IEEE Signal Processing Letters, 2022, 29, 444-448. | 3.6 | 19 |
| 11 | A Low-Voltage, Low-Current, Digital-Driven MEMS Mirror for Low-Power LiDAR. , 2020, 4, 1-4. | | 16 |
| 12 | Wideband Capacitance Evaluation of Silicon–Insulator–Silicon Through-Silicon-Vias for 3D Integration Applications. IEEE Electron Device Letters, 2016, 37, 216-219. | 3.9 | 14 |
| 13 | Comparative evaluations on scallop-induced electric-thermo-mechanical reliability of through-silicon-vias. Microelectronics Reliability, 2019, 103, 113512. | 1.7 | 14 |
| 14 | Development of Eccentric Spin Coating of Polymer Liner for Low-Temperature TSV Technology With Ultra-Fine Diameter. IEEE Electron Device Letters, 2019, 40, 95-98. | 3.9 | 14 |
| 15 | Phase-change metasurface for switchable vector vortex beam generation. Optics Express, 2021, 29, 42762. | 3.4 | 13 |
| 16 | Investigation on mechanism of polymer filling in high-aspect-ratio trenches for through-silicon-via (TSV) application. Science China Technological Sciences, 2014, 57, 1616-1625. | 4.0 | 12 |
| 17 | Study of Vacuum-Assisted Spin Coating of Polymer Liner for High-Aspect-Ratio Through-Silicon-Via Applications. IEEE Transactions on Components, Packaging and Manufacturing Technology, 2016, 6, 501-509. | 2.5 | 12 |
| 18 | Innovative polyimide liner deposition method for high-aspect-ratio and high-density through-silicon-vias (TSVs). Microelectronic Engineering, 2016, 149, 78-84. | 2.4 | 12 |

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| # | Article | IF | CITATIONS |
|----|---|-----|-----------|
| 19 | Modelling and Experimental Verification of Step Response Overshoot Removal in Electrothermally-Actuated MEMS Mirrors. Micromachines, 2017, 8, 289. | 2.9 | 12 |
| 20 | Optically stimulated synaptic transistor based on MoS ₂ /quantum dots mixed-dimensional heterostructure with gate-tunable plasticity. Optics Letters, 2021, 46, 1748. | 3.3 | 12 |
| 21 | Flexible Broadband Photodetectors Enabled by MXene/PbS Quantum Dots Hybrid Structure. IEEE Electron Device Letters, 2021, 42, 1814-1817. | 3.9 | 12 |
| 22 | An Efficient Algorithm for Direction Finding against Unknown Mutual Coupling. Sensors, 2014, 14, 20064-20077. | 3.8 | 11 |
| 23 | Extended Transformed Nested Arrays for DOA Estimation of Non-Circular Sources. IEEE Access, 2020, 8, 162350-162362. | 4.2 | 11 |
| 24 | Elimination of Scallop-Induced Stress Fluctuation on Through-Silicon-Vias (TSVs) by Employing Polyimide Liner. IEEE Transactions on Device and Materials Reliability, 2018, 18, 266-272. | 2.0 | 10 |
| 25 | Enabling Continuous Cu Seed Layer for Deep Through-Silicon-Vias With High Aspect Ratio by Sequential Sputtering and Electroless Plating. IEEE Electron Device Letters, 2021, 42, 1520-1523. | 3.9 | 10 |
| 26 | Low capacitance and highly reliable blind through-silicon-vias (TSVs) with vacuum-assisted spin coating of polyimide dielectric liners. Science China Technological Sciences, 2016, 59, 1581-1590. | 4.0 | 9 |
| 27 | Coupled Thermo-Mechanical Analysis of 3D ICs Based on an Equivalent Modeling Methodology With Sub-Modeling. IEEE Access, 2020, 8, 14146-14154. | 4.2 | 9 |
| 28 | A Compact Omnidirectional Laser Scanner Based on an Electrothermal Tripod Mems Mirror for Lidar Please Leave. , 2019, , . | | 8 |
| 29 | Analog-controlled light microshutters based on electrothermal actuation for smart windows. Optics Express, 2020, 28, 33106. | 3.4 | 8 |
| 30 | Thermal reliability analysis and optimization of polymer insulating through-silicon-vias (TSVs) for 3D integration. Science China Technological Sciences, 2014, 57, 128-135. | 4.0 | 7 |
| 31 | Investigation of dynamic thermal behaviors of an electrothermal micromirror. Sensors and Actuators A: Physical, 2017, 263, 269-275. | 4.1 | 7 |
| 32 | A Piezoelectric MEMS Loud Speaker Based on Ceramic PZT. , 2019, , . | | 7 |
| 33 | Study on atomic migration of copper through-silicon-vias with Bosch scallops. Microelectronics Reliability, 2021, 123, 114178. | 1.7 | 6 |
| 34 | Highly conformal polyimide liner deposition in highâ€aspectâ€ratio through silicon vias. Micro and Nano Letters, 2016, 11, 253-255. | 1.3 | 5 |
| 35 | A Novel Silicon-Air-Silicon Through-Silicon-Via Structure Realized Using Double-Side Partially Overlapping Etching. IEEE Electron Device Letters, 2020, 41, 1544-1547. | 3.9 | 5 |
| 36 | Electrical characteristics and thermal reliability of blind through-silicon-vias with polyimide liners. , | | 4 |

2016, , .

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| # | Article | IF | CITATIONS |
|----|--|------|-----------|
| 37 | Ultra-Deep Annular Cu Through-Silicon-Vias Fabricated Using Single-Sided Process. IEEE Electron Device Letters, 2022, 43, 426-429. | 3.9 | 4 |
| 38 | Low cost polyimide liner formation with vacuum-assisted spin coating for through-silicon-vias. , 2016, , . | | 3 |
| 39 | Impact of polyimide liner on high-aspect-ratio through-silicon-vias (TSVs): electrical characteristics and copper protrusion. Microsystem Technologies, 2017, 23, 3757-3764. | 2.0 | 3 |
| 40 | Sampling and Reconstruction of Multiband Signals in Multiresolution Subspaces Associated with the Fractional Wavelet Transform. IEEE Signal Processing Letters, 2018, , 1-1. | 3.6 | 3 |
| 41 | Design and Evaluation of a Novel and Ultra-Compact Fully-TGV-based Self-Shielding Bandpass Filter for 5G Applications. , 2019, , . | | 3 |
| 42 | Development of Cu Seed Layers in Ultra-High Aspect Ratio Through-Silicon-Vias (TSVs) with Small Diameters. , 2021, , . | | 3 |
| 43 | Cell trapping and patterning using dielectric-structure-assisted negative dieletrophoresis. Science China Technological Sciences, 2013, 56, 1001-1007. | 4.0 | 2 |
| 44 | A Fully Integrated K-Band Dual Down-Conversion Receiver for Radar Applications in 90 nm CMOS. IEEE Access, 2020, 8, 19576-19589. | 4.2 | 2 |
| 45 | An All-Wet, Low Cost RDL Fabrication Process with Electroless Plated Seed/Barrier Layers. , 2021, , . | | 2 |
| 46 | A large-piston scanning electrothermal micromirror with a temperature control frame. , 2016, , . | | 1 |
| 47 | A 25–35 GHz 5-bit digital attenuator with low RMS amplitude error and low phase variation in 65 nm CMOS. IEICE Electronics Express, 2019, 16, 20190394-20190394. | 0.8 | 1 |
| 48 | Anisotropic electrical properties of aligned PtSe2 nanoribbon arrays grown by a pre-patterned selective selenization process. Nano Research, 0, , 1. | 10.4 | 1 |
| 49 | Design of a dynamically reconfigurable arithmetic unit for matrix algorithms. , 2015, , . | | 0 |
| 50 | An analytical model for capacitance of silicon-insulator-silicon through-silicon-vias. , 2016, , . | | 0 |
| 51 | Stiffness-Tunable Microstructures Based on Electrothermal Bimorph Beams. , 2021, , . | | 0 |
| 52 | A Low-Cost and Low-Temperature Method to Realize Carbon Nanotube Conductor in Through-Silicon-Via. , 2021, , . | | 0 |
| 53 | Paper-based flexible broadband photodetectors functionalized by PbS quantum dots/Carbon nanotube networks hybrid structure. , 2021, , . | | 0 |